

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

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In re Patent Application of:  
Richard A. Haight, et al.

Application No.: Not Yet Assigned

Confirmation No.:

Filed: Concurrently Herewith

Art Unit: N/A

For: **METHOD AND APPARATUS FOR REPAIR  
OF REFLECTIVE PHOTOMASKS**

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Examiner: Not Yet Assigned

**INFORMATION DISCLOSURE STATEMENT (IDS)**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Pursuant to 37 CFR 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO/SB/08. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement accompanies the new patent application submitted herewith.

A copy of each reference on PTO/SB/08 is attached.

The Director is hereby authorized to charge any deficiency in the fees filed, asserted to be filed or which should have been filed herewith (or with any paper hereafter filed in this

Application No.: Not Yet Assigned

Docket No.: 20140-00303-US1

application by this firm) to IBM Deposit Account No. 09-0456, under Order No. 20140-00303-US1. A duplicate copy of this paper is enclosed.

Dated: September 12, 2003  
284494\_1

Respectfully submitted,

By Larry J. Hume  
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Substitute for form 1449A/B/PTO				<b>Complete if Known</b>	
				Application Number	Not Yet Assigned
				Filing Date	Concurrently Herewith
				First Named Inventor	Richard A. Haight
				Art Unit	N/A
				Examiner Name	Not Yet Assigned
Sheet	1	of	1	Attorney Docket Number	20140-00303-US1

<b>U.S. PATENT DOCUMENTS</b>					
Examiner Initials*	Cite No. <sup>1</sup>	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code <sup>2</sup> (if known)			
AA	US-6333485		12/25/01	Haight et al.	
AB	US-6190836		2/20/01	Grenon et al.	
AC	US-6165649		12/26/00	Grenon et al.	
AD	US-6156461		12/05/00	Grenon et al.	
AE	US-6050907		04/18/00	Long	
AF	US-5656186		08/12/97	Mourou et al.	

<b>FOREIGN PATENT DOCUMENTS</b>					
Examiner Initials*	Cite No. <sup>1</sup>	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Country Code <sup>3</sup> -Number <sup>4</sup> -Kind Code <sup>5</sup> (if known)			
					T <sup>6</sup>

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. <sup>1</sup>Applicant's unique citation designation number (optional). <sup>2</sup>See Kinds Codes of USPTO Patent Documents at [www.uspto.gov](http://www.uspto.gov) or MPEP 901.04. <sup>3</sup>Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). <sup>4</sup>For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. <sup>5</sup>Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. <sup>6</sup>Applicant is to place a check mark here if English language Translation is attached.

<b>NON PATENT LITERATURE DOCUMENTS</b>					
Examiner Initials	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.			T <sup>2</sup>
	CA	MARS2: An Advanced Femtosecond Laser Mask Repair Tool, A. Wagner, R. Haight, P. Longo, SPIE, 42, 457 (2002)			
	CB	Femtosecond Laser Mask Repair, A. Wagner, R. Haight, P. Longo, M. Schmidt, P. Flanigan, D. Thibault, <i>Microlithog. World</i> , 12, 6, 2003			
	CC	Femtosecond Lasers Repair Photomasks, R. Haight, P. Longo, A. Wagner, <i>Laser Focus World</i> , May 2002			
	CD	MARS: A Femtosecond Laser Mask Advanced Repair System in Manufacturing, R. Haight, D. Hayden, P. Longo, T. Neary, A. Wagner, <i>J. Vac. Sci. Technol.</i> , B 17, 3137 (1999).			
	CE	Implementation and Performance of a Femtosecond Laser Mask Repair System In Manufacturing, R. Haight, D. Hayden, P. Longo, T. Neary, A. Wagner, SPIE, 3546, 477, 1998.			

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

<sup>1</sup>Applicant's unique citation designation number (optional). <sup>2</sup>Applicant is to place a check mark here if English language Translation is attached.

Examiner Signature	Date Considered
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